

2. (amended) A microelectromechanical positioner, comprising:  
a substrate;  
a moveable platform;  
at least one linkage mechanism having a plurality of links, wherein the linkage mechanism is pivotably attached to the substrate by at least two anchor links and pivotably attached to the moveable platform by at least two platform links, and whereby the platform is constrained to exhibit substantially translational movement in a plane; and  
at least one actuator operatively connected to provide movement thereof to at least one of the group consisting of a linkage mechanism, an anchor link, a platform link, and the platform, wherein the at least one actuator selected is from the group consisting of electrostatic actuators, electromagnetic actuators, and thermal actuators.
10. (amended) The microelectromechanical positioner of Claim 1, wherein the rotary actuator comprises an electrostatic actuator.
11. (amended) The microelectromechanical positioner of Claim 1 or 2, further comprising at least one spring operatively connected to the platform to restore the platform to a rest position in the absence of actuation of the actuator.

#### REMARKS

Attached hereto is a marked-up version of the changes made to the claims by the current amendment. The attached page is captioned "Version with markings to show changes made."

In further support of the claims presented, Applicants provide the following discussion.

#### STATUS OF THE CLAIMS

Claims 1-7 and 10-15 remain in this application.

The Office rejected Claims 1, 3/1, 4/1, 12/1, and 13/1 under 35 U.S.C. § 102(a) as being anticipated by *Ono, Corbett, or Martin*.

The Office rejected Claims 2, 3/2, 4/2, 8, 12/2, and 13/2 under 35 U.S.C. § 102(a) as being anticipated by *Hatamura*.